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Substitute for form 1449APTO
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(Use of party): heats as necessary)

Application Number 09/945500

Filing Date August 30, 2001

First Named Inventor Forbes, Leonard

Group Art Unit 2818

Examiner Name Pham, Ly

Attorney Docket No: 1303.029US1

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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
TO SEE ASS. PIZZY, Sheets as necessary)

Complete if Known	
Application Number	09/945500
Filing Date	August 30, 2001
First Named Inventor	Forbes, Leonard
Group Art Unit	2818
Examiner Name	Pham, Ly
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